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PATENT
ATTORNEY DOCKET NO. 46884-5461

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Kenshi FUKUMITSU et al.) Confirmation No.: 3680
)
U.S. Application No.: 10/571,142) Group Art Unit: 2811
)
Filed: March 9, 2006) Examiner: Unassigned
)
For: SEMICONDUCTOR SUBSTRATE CUTTING)
METHOD)

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Window Mail Stop: New Application Amendment AF Issue Fee
Alexandria, VA 22314

Sir:

INFORMATION DISCLOSURE STATEMENT (IDS)

Under 37 C.F.R. § 1.97(b): Pursuant to 37 C.F.R. §§ 1.56 and 1.97(b), Applicant brings to the attention of the Examiner the documents listed on the attached PTO Form 1449. To the undersigned's knowledge, this IDS is being filed before the mailing date of a first Office Action on the merits, before the mailing date of a first Office Action on the merits after filing an RCE under § 1.114, or within three months of the application filing date.

Under 37 C.F.R. § 1.97(c): Pursuant to 37 C.F.R. §§ 1.56 and 1.97(c), Applicant brings to the attention of the Examiner the documents listed on the attached PTO Form 1449. This IDS is being filed after the events recited in § 1.97(b) but, to the undersigned's knowledge, before the mailing date of a Final Office Action, a Notice of Allowance, or another action that closes prosecution in the application.

The fee of \$180.00 set forth in § 1.17(p) is included herein; or
 Applicant submits that each item of information contained in this IDS was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this IDS.

Under 37 C.F.R. § 1.97(d): Pursuant to 37 C.F.R. §§ 1.56 and 1.97(d), Applicant brings to the attention of the Examiner the documents listed on the attached PTO Form 1449. This IDS is being filed after the events recited in § 1.97(c) but before payment of the issue fee.

The fee of \$180.00 set forth in § 1.17(p) is included herein; and
 Applicant submits that each item of information contained in this IDS was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this IDS.

Under 37 C.F.R. § 1.97(i): Pursuant to 37 C.F.R. §§ 1.56 and 1.97(i), Applicant brings to the attention of the Examiner the documents listed on the attached PTO Form 1449. This IDS is being filed after the events recited in § 1.97(d). Applicant requests that the IDS be placed in the file.

A search report or other listing of documents from a counterpart, related, or other application dated _____ and having documents cited thereon is attached for the Examiner's consideration. Any of these documents not previously cited, and any additional documents are listed on the PTO Form 1449.

Applicant respectfully requests that the Examiner consider the listed documents and evidence that consideration by making appropriate notations on the attached form. As for any document listed on the accompanying PTO-1449 that is in a language other than English, relevance can be understood from an enclosed English abstract or at least partial translation or from mention in the specification or in a search report for a corresponding application.

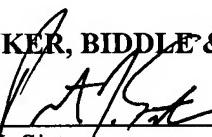
This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that any of the listed documents are material or constitute "prior art." If it should be determined that any of the listed documents do not constitute "prior art" under United States law, Applicant reserve the right to present to the Office the relevant facts and law regarding the appropriate status of such documents.

Applicant further reserves the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should any of the documents be applied against the claims of the present application.

Except for issue fees payable under 37 C.F.R. § 1.18, the Commissioner is hereby authorized by this paper to charge any additional fees during the entire pendency of this Application, including fees due under 37 C.F.R. § 1.16 and 1.17 which may be required and including any required extension of time fees, or credit any overpayment to Deposit Account No. 50-0573. This paragraph is intended to be a CONSTRUCTIVE PETITION FOR EXTENSION OF TIME in accordance with 37 C.F.R. § 1.136(a)(3).

Respectfully submitted,

DRINKER, BIDDLE & REATH LLP


Peter J. Sistare
Registration No. 48,183

Dated: July 31, 2007

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JUL 31 2007

INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Attorney Docket No.:
46884-5461

Serial No.:
10/571,142

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PTO Form 1449

Filing Date:
March 9, 2006

Group Art Unit:
2811

U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Sub Class	Filing Date
	2004/0002199	Jan. 1, 2004	Fukuyo et al.	-	-	
	6,992,026	Jan. 31, 2006	Fukuyo et al.	-	-	
	2006/0148212	July 6, 2006	Fukuyo et al.	-	-	
	3,610,871	Oct. 5, 1971	Lumley	-	-	
	3,626,141	Dec. 7, 1971	Daly	-	-	
	3,629,545	Dec. 21, 1971	Graham et al.	-	-	
	3,790,051	Feb. 5, 1974	Moore	-	-	
	4,242,152	Dec. 30, 1980	Stone	-	-	
	4,531,060	Jul. 23, 1985	Suwa et al.	-	-	
	5,230,184	Jul. 27, 1993	Bukhman	-	-	
	5,841,543	Nov. 24, 1998	Guldi et al.	-	-	
	5,925,271	Jul. 20, 1999	Pollack et al.	-	-	
	5,968,382	Oct. 19, 1999	Matsumoto et al.	-	-	
	5,976,392	Nov. 2, 1999	Chen	-	-	
	6,031,201	Feb. 29, 2000	Amako et al.	-	-	
	6,175,096	Jan. 16, 2001	Nielsen	-	-	
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	6,285,002	Sep. 4, 2001	Ngoi et al.	-	-	
	6,325,855	Dec. 4, 2001	Sillmon et al.	-	-	
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	2005/0189330	Sep. 1, 2005	Fukuyo et al.	-	-	
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	2006/0040473	Feb. 23, 2006	Fukuyo et al.	-	-	

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	Document Number	Date	Country	Class	Sub Class	Translation YES	NO
	WO 02/22301 A1	March 21, 2002	PCT			Abstract	
	165354	Aug. 1, 1991	Taiwan			Abstract	
	192484	Oct. 11, 1992	Taiwan			Abstract	
	219906	Feb. 1, 1994	Taiwan			Abstract	
	WO 2004/082006	Sep. 23, 2004	PCT			Abstract	
	0 863 231	Sep. 9, 1998	Europe				
	2001-017690	Mar. 5, 2001	Korea			Abstract	
	59-130438	Jul. 27, 1984	Japan			Abstract	
	60-144985	Jul. 31, 1985	Japan			Abstract	
	62-004341	Jan. 10, 1987	Japan			Abstract	
	64-038209	Feb. 8, 1989	Japan			Abstract	
	03-276662	Dec. 6, 1991	Japan			Abstract	

Examiner

Date Considered

Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)		Attorney Docket No.: 46884-5461	Serial No.: 10/571,142
PTO Form 1449		Applicants Kenshi FUKUMITSU et al.	Page 2 of 6
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*Examiner Initial	Document Number	Date	Name	Class	Sub Class	Filing Date
	5,656,186	August 12, 1997	Mourou et al.	-	-	
	5,543,365	August 6, 1996	Wills et al.	-	-	
	2004/0002199 A1	January 1, 2004	Fukuyo et al.	-	-	
	5,211,805	May 18, 1993	Srinivasan	-	-	

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	04-029352	Jan. 31, 1992	Japan			Abstract	
	04-300084	Oct. 23, 1992	Japan			Abstract	
	08-197271	Aug. 6, 1996	Japan			Abstract	
	09-260310	Oct. 3, 1997	Japan			Abstract	
	10-071483	Mar. 17, 1998	Japan			Abstract	
	10-214997	Aug. 11, 1998	Japan			Abstract	
	10-233373	Sep. 2, 1998	Japan			Abstract	
	11-071124	Mar. 16, 1999	Japan			Abstract	
	2000-216114	Aug. 4, 2000	Japan			Abstract	
	2000-210785	Aug. 2, 2000	Japan			Abstract	
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	2000-237886	Sep. 5, 2000	Japan			Abstract	
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	2001-326194	Nov. 22, 2001	Japan			Abstract	
	2002-192368	Jul. 10, 2002	Japan			Abstract	
	2002-205181	Jul. 23, 2002	Japan			Abstract	
	2002-224878	Aug. 13, 2002	Japan			Abstract	
	2005-047290	Feb. 24, 2005	Japan			Abstract	
	2005-313237	Nov. 10, 2005	Japan			Abstract	
	JP 8-264488	Oct. 11, 1996	Japan			Abstract	
	JP 9-017831	Jan. 17, 1997	Japan			Abstract	
	JP 11-121517	Apr. 30, 1999	Japan			Abstract	
	WO 03/076118	Sep. 18, 2003	Japan			Abstract	

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(Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.)

	A. Ishii et al., CO2 Laser Processing Technology, Nikkan Kogyo Publishing Production, Dec. 21, 1992, pp. 63-65 (with partial English translation)
Examiner	Date Considered

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		Document Number	Date	Country	Class	Sub Class	<u>Translation</u> YES NO
		JP 2006-135355	May 25, 2006	Japan			Abstract
		JP 4-188847	July 7, 1992	Japan			Abstract
		JP 7-263382	October 13, 1995	Japan			Abstract
		JP 9-263734	October 7, 1997	Japan			Abstract
		JP 2006-128723	May 18, 2006	Japan			Abstract
		JP 2002-192367	July 10, 2002	Japan			Abstract
		JP 2000-042764	February 15, 2000	Japan			Abstract
		JP 5-335726	December 17, 1993	Japan			Abstract
		11-162889	June 18, 1999	Japan			Abstract
		61-121453	Sept. 6, 1986	Japan			Abstract
		2005-001001	Jan. 6, 2005	Japan			Abstract
		2003-334812	Nov. 25, 2003	Japan			Abstract
		2000-042764	Feb. 15, 2000	Japan			Abstract
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		2003-338467	Nov. 28, 2003	Japan			Abstract
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		WO 02/07927 A1	January 31, 2002	PCT			
		10-305420	November 17, 1998	JP			Abstract
		04-111800	April 13, 1992	JP			Abstract
		09-017756	January 17, 1997	JP			Abstract
		07-037840	February 7, 1995	JP			Abstract
		2000-124537	April 28, 2000	JP			Abstract

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*Examiner Initial	Document Number	Date	Name	Class	Sub Class	Filing Date
	4,562,333	Dec. 31, 1985	TAUB et al.	-	-	
	5,254,833	Oct. 19, 1993	OKIYAMA	-	-	
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	5,211,805	May 18, 1993	SRINIVASAN	-	-	

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	Document Number	Date	Country	Class	Sub Class	<u>Translation</u>	<u>YES</u>	<u>NO</u>
	46-24989 (corresponding to U.S. 3,629,545)	July 19, 1971	JP					

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(Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.)

	"New Laser Handbook" published by Asakusa Shoten, June 15, 1989, pp. 666-669, including English language translation
	Tooling Machine Series, "Laser Machining" published by Taiga Shuppan Inc., 1990, pp. 91-96, including English language translation
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	Journal of the Japan Society of Griding Engineers, Vol. 47, No. 5, May (2003), pp. 229-231, including English language translation
	T. Miyazaki, "Laser Beam Machining Technology," Published by Sangyo-Tosho Inc., May 31, 1991, First Edition. pp. 9-10.

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		2002-158276 A	May 31, 2002	JP			Abstract	
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		2005/0184037	August 25, 2005	Fukuyo et al.	-	-	

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		11-163403 A	Jun. 18, 1999	JP			X		
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Katsumi MIDORIKAWA. "Recent Progress of Femtosecond Lasers and Their Applications to Material Processing", Dai 45 Kai Laser Netsukako Kenkyukai Ronbunshu, December 1998, pp. 29-38.

T. Sano et al., "Ultrashort Pulse Laser Microprocessing of Silicon", Japan Welding Society Zenkoku Taikai Koen Gaiyo, March 2000, pp. 72-73.

K. Miura et al., "Formation of Photo-induced Structures in Glasses with Femtosecond Laser," Dai 42 Kai Laser Netsukako Kenkyukai Ronbunshu, November 1997, pp. 107, line 4 to pp. 109, line 5.

K. Hayashi, "Inner Glass Marking by Harmonics of Solid-state Laser", Dai 45 Kai Laser Netsukako Kenkyukai Ronbunshu, December 1998, pp. 23-28.

"Proceedings of the 63rd Laser Materials Processing Conference", May 2005, pp. 115-123.

The 6th International Symposium on Laser Precision Microfabrication, April 2005.

"Journal of Japan Laser Processing Society", Vol. 12, No. 1, February 2005, pp. 115-123.

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